

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S9	55	(semi\$1conductor work\$1piece wafer substrate) near5 transfer and (process near3 (chamber unit)) near4 (stacked stack tower (on adj top adj of) ((dispos\$3 arrang\$5) near2 vertical\$2)) and (semi\$1conductor work\$1piece wafer substrate) near5 (coat coating deposit deposition) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/08 17:26
S11	43	(coating near3 (chamber unit)) near4 (stacked stack tower (on adj top adj of) ((dispos\$3 arrang\$5) near2 vertical\$2)) and (semi\$1conductor work\$1piece wafer substrate) near5 (coat coating deposit deposition) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/08 15:27
S26	99	(process near3 (chamber unit)) near4 (stacked stack tower (on adj top adj of) ((dispos\$3 arrang\$5) near2 vertical\$2)) and (semi\$1conductor work\$1piece wafer substrate) near5 (coat coating deposit deposition) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/09 09:52
S34	124	((processing process) near3 (area section unit zone)) near4 (detach detaches detached detachable separate separates separable) and (semi\$1conductor work\$1piece wafer substrate) near5 (coat coating deposit deposition cvd pvd) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/09 11:18
S35	14	((processing process) near3 (area section unit zone)) near4 (detach detaches detached detachable separable) and (semi\$1conductor work\$1piece wafer substrate) near5 (coat coating deposit deposition cvd pvd) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/09 11:19
S47	142	(air near3 (passage passageway conduit)) near5 (heating heater) and (semi\$1conductor work\$1piece wafer substrate) and (coat coating deposit deposition) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/09 15:46
S48	10	(air near4 (insulate insulation)) near5 (heating heater) and (semi\$1conductor work\$1piece wafer substrate) and (coat coating deposit deposition) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/09 16:09
S55	70	(air near5 between near6 heater) same (insulate insulation)	US-PGPUB; USPAT	OR	ON	2007/08/09 16:34
S56	190	(air near5 between near6 heater) and @py<"2003" and (substrate wafer)	US-PGPUB; USPAT	OR	ON	2007/08/09 16:38
S58	31	((air near2 (passage passageway conduit)) near5 heater) same (insulate insulation)	US-PGPUB; USPAT	OR	ON	2007/08/09 16:40
S59	26	((air near2 (passage passageway conduit)) near5 heater) same (insulate insulation) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/09 16:43

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S60	243	(air near2 (passage passageway conduit)) near5 (insulate insulation) and @py<"2003"	US-PGPUB; USPAT	OR	ON	2007/08/09 16:44
S61	28	(air near2 (passage passageway conduit)) near5 (insulate insulation) and @py<"2003" and (substrate wafer work\$1piece)	US-PGPUB; USPAT	OR	ON	2007/08/09 16:58
S63	18	(passage passageway conduit) near9 (insulate insulation) near9 heater and @py<"2003" and (substrate wafer work\$1piece)	US-PGPUB; USPAT	OR	ON	2007/08/21 07:59
S73	69	electron near3 beam and electron near3 irradiat\$3 and electron with (cure curing) and @py<"2003" and ((insulating adj film) insulation) and (substrate wafer work\$1piece)	US-PGPUB; USPAT	OR	OFF	2007/08/20 16:33
S75	188	electron near3 beam and electron near10 (cure curing) and @py<"2003" and (substrate wafer work\$1piece) and ((insulating adj film) insulation)	US-PGPUB; USPAT	OR	OFF	2007/08/20 16:40
S76	29	electron near3 beam and electron near10 (cure curing) and @py<"2003" and (substrate wafer work\$1piece) and (insulating adj film)	US-PGPUB; USPAT	OR	OFF	2007/08/21 08:00